

**IN THE SPECIFICATION**

1. Please amend paragraph [0033] as follows:

[0033] In some embodiments, the different shapes of the objects in the second portion 204 identify different types of resources 115 in the semiconductor fabrication facility, and the shading or color of an object identifies the status of the resource 115 associated with that object. In this example, the second portion 204 of the GUI 140 includes irregular shaped objects 208a-208b representing different wet decks in the semiconductor fabrication facility. The objects 208, such as object 208a, without ~~crosshatches~~ hatching represent wet decks that are up and available for use. The objects 208, such as object 208b, with ~~crosshatches~~ hatching represent wet decks that are down and unavailable for use.

2. Please amend paragraph [0034] as follows:

[0034] The second portion 204 of the GUI 140 also includes circular objects 210a-210c representing horizontal furnaces in the semiconductor fabrication facility. The horizontal furnaces may include gate ox furnaces, tunnel ox furnaces, clean ox furnaces, and doped ox furnaces. The objects 210, such as object 210a, with dots or shading and ~~crosshatches~~ hatching represent furnaces that are unavailable for use. The ~~lightly-shaded~~ objects 210, such as object 210b, with no shading or lighter shading represent furnaces that are operational and available for use. The ~~darker-shaded~~ objects 210, such as object 210c, with dots or darker shading represent furnaces that are operational and actually in use. Any color or shading can be used to represent the status of a resource 115.

3. Please amend paragraph [0036] as follows:

[0036] The second portion 204 of the GUI 140 further includes square objects 212a-212c representing vertical furnaces in the semiconductor fabrication facility. A vertical furnace could, for example, represent a vertical polysilicon furnace (also referred to as a vertical poly furnace). The objects 212, such as object 212a, with ~~crosshatches~~ hatching represent unavailable vertical furnaces. The objects 212, such as object 212b, with no shading or lighter shading represent idle and available vertical furnaces. The objects 212, such as object 212c, with dots or darker shading represent vertical furnaces that are currently in use.

4. Please amend paragraph [0053] as follows:

[0053] A status indicator 370 identifies whether a wafer lot is actively being processed by resources 115 in the semiconductor fabrication facility or is waiting to be processed. An owning entity 372 identifies the resource 115 that is currently processing a wafer lot. A current operation identifier [[372]] 374 represents a numeric indicator for the operation being performed by the resource 115 that is processing a wafer lot. A current operation description [[374]] 376 describes the operation being performed by the resource 115 that is processing a wafer lot. A current quad 378 identifies the type of operation being performed by the resource 115 that is processing a wafer lot. In this example, the current quad 378 includes diffusion and etching operations, although any other or additional types of operations could be performed.